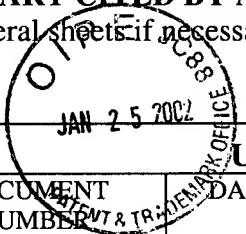
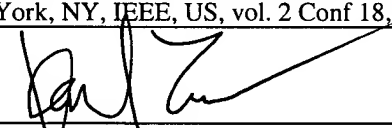
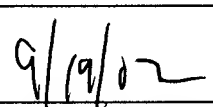
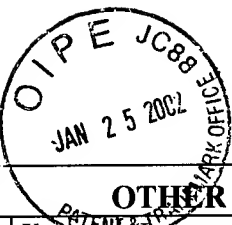


FORM PTO-1449 U.S. DEPARTMENT OF COMMERCE										AGENT DOCKET NO. <b>ONX-106A</b>		SERIAL NO. <b>09/810,336</b>			
<b>LIST OF PRIOR ART CITED BY APPLICANT</b> (Use several sheets if necessary)										APPLICANT <b>Behrang Behin et al.</b>					
										FILING DATE <b>3/14/2001</b>		GROUP <b>2811</b>			
<div style="text-align: center;">  <b>U.S. PATENT DOCUMENTS</b> </div>															
EXAMINER INITIAL		DOCUMENT NUMBER							DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE		
<i>but</i>	A	5	7	2	3	3	5	3	3/3/1998	Muenzel et al.	437	51	2/12/1996		
<i>but</i>	B	5	7	2	6	0	7	3	3/10/1998	Zhang et al.	437	228	1/16/1996		
<i>but</i>	C	5	7	5	3	9	1	1	5/19/1998	Yasuda et al.	250	306	1/16/1997		
<i>but</i>	D	5	8	7	2	8	8	0	2/16/1999	Maynard	385	88	8/12/1996		
<i>but</i>	E	6	3	3	0	1	0	2	12/11/2001	Daneman et al.	359	290	3/25/2000		
<i>but</i>	F	5	9	5	9	7	6	0	9/28/1999	Yamada et al.	359	224	7/28/1998		
<b>FOREIGN PATENT DOCUMENTS</b>															
		DOCUMENT NUMBER							DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION		
													YES	NO	
<i>but</i>	G	0	9	0	7	0	7	6	A 2	4/7/1999	Europe	G01N	27/00		
<i>but</i>	H	0	9	0	7	0	7	6	A 3	10/4/2000	Europe	H01J	37/63		
<i>but</i>	I	0	9	1	1	9	5	2	A 2	4/28/1999	Europe	H02N	1/00		
<i>but</i>	J	0	9	1	1	9	5	2	A 3	4/5/2000	Europe	H02N	1/00		
<i>but</i>	K	1	9	7	5	7	1	8	1 A	7/1/1997	Germany	G02B	6/35		X
<i>but</i>	L	1	9	6	4	4	9	1	8 A	4/30/1998	Germany	G02B	6/35	X	
<i>but</i>	M	2	9	6	1	1	8	8	1 8	12/12/1996	Germany	G02B	6/35		X
<i>but</i>	O	2	7	3	2	4	6	7	A 1	4/10/1996	France	G01P	15/08		X
<b>OTHER PRIOR ART (Including Author, Title, Date, Pertinent Pages, Etc.)</b>															
<i>but</i>	N	"Electrostatic Comb Drive For Vertical Actuation" A.P. Lee et al., Proceedings of the SPIE, SPIE, Bellingham, VA, vol. 3224, Sept 29, 1997, pp 109-119													
<i>but</i>	P	"Design, Fabrication, Position Sensing, And Control Of An Electrostatically-Driven Polysilicon Microactuator," P. Cheung et al, IEEE Transactions on Magnetics, vol. 32, no. 1, 1 Jan. 1996, pp 122-128													
<i>but</i>	Q	"Optical Methods For Micromachine Monitoring And Feedback", F.M. Dickey et al., Sensors and Actuators, vol. 78, 1999, pp 220-235													
<i>but</i>	R	"A High Sensitivity Z-Axis Capacitive Silicon Microaccelerometer with a Torsional Suspension", Selvakumar et al., Journal of Microelectromechanical Systems, IEEE Inc., New York, vol. 7, No. 2, June 1998, pp 192-200													
<i>but</i>	S	"MEMS Fabrication of High Aspect Ratio Track-Following Micro Actuator for Hard Disk Drive Using Silicon On Insulator", B. H. Kim et al., Technical Digest of the IEEE International MEMS '99 Conference. 12 <sup>th</sup> IEEE International Conference on Micro Electro Mechanical Systems. Orlando, FL, Jan 17-21, 1999, IEEE International Micro Electro Mechanical Systems Conference, New York, NY, 1999, pp 53-56.													
<i>but</i>	T	"Fabrication of Comb-Shaped Microactuator for Multi-Degrees-of-Freedom System", F. Fujikawa et al., Robotics, CIM and Automation, Emerging Technologies, San Diego, Nov. 9-13, 1992, Proceedings of the International Conference on Industrial Electronics, Control, Instrumentation and Automation (IECON), New York, NY, IEEE, US, vol. 2 Conf 18, 9 November 1992, pp 990-995													
EXAMINER										DATE CONSIDERED					
															
* EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.															

**OTHER PRIOR ART** (Including Author, Title, Date, Pertinent Pages, Etc.)

7	<del>but</del>	U	Integrated Micro-Scanning Tunneling Microscope", Xu et al., Applied Physics Letters, American Institute of Physics, New York, vol. 67, No. 16, October 16, 1995 pp 2305-2307.
8	<del>but</del>	V	B. Behin et al., US Published Patent Application US-2001-002001-0048784-A1, Published Dec. 6, 2001, Serial No. 09/751,660 "Two-Dimensional Gimbaled Scanning Actuator with Vertical Electrostatic Comb-Drive for Actuation and/or Sensing" Filed Dec 28, 2000 (ONX-105)
9	<del>but</del>	W	B. Behin et al., US Patent Application Serial No. 09/809,994 "Biased Rotatable Combdribe Actuator Methods" Filed March 14, 2001 (ONX-106B)
10	<del>but</del>	X	B. Behin et al., US Published Patent Application US-2001-002001-0040419-A1, Published Nov. 15, 2001, Serial No. 09/809,995 "Biased Rotatable Combdribe Sensor Methods", Filed March 14, 2001 (ONX-106C)
11	<del>but</del>	Y	B. Behin et al., US Published Patent Application, US-2001-002001-0051014-A1, Published Dec. 13, 2001, Serial No. 09/810,326 "Optical Switch Employing Biased Rotatable Combdribe Devices and Methods", Filed March 14, 2001 (ONX-106D)
12	<del>but</del>	Z	B. Behin et al., US Patent Application Serial No. 09/810,333 "Multi-Layer, Self-Aligned Vertical Combdribe Electrostatic Actuators And Fabrication Methods", Filed March 14, 2001 (ONX-107A)
13	<del>but</del>	AA	B. Behin et al., US Published Patent Application US-2001-002001-0034938-A1, Serial No. 09/810,335 "Multi-Layer, Self-Aligned Vertical Combdribe Electrostatic Actuators And Fabrication Methods", Filed March 14, 2001 (ONX-107B)
14	<del>but</del>	AB	"Vertical Comb Array MicroActuators", A. Selvakumar et al., Proceedings of the Workshop on Micro Electrical Mechanical Systems (MEMS), Amsterdam, New York, Jan 29-Feb 2, 1995, IEEE Vol. Workshop 8 Jan. 29, 1995, pp 43-48, ISBN 0-7803-2504-4
15	<del>but</del>	AC	"Fabrication of a 3D Differential-Capacitive Acceleration Sensor by UV-LIGA", W. Qu et al., Sensors and Actuators 77 (1999), pp 14-20, Elsevier Science, 0924-4247/99/\$
16	<del>but</del>	AD	"Integrating SCREAM Micromachined Devices with Integrated Circuits", K.A. Shaw, N.C MacDonald, IEEE MEMS '96, San Diego, California 1996, IEEE Publication 0-7803-2985-6/96, pp 44-48
17	<del>but</del>	AE	"An electrostatically excited 2D-Micro-Scanning-Mirror with an in-plane configuration of the driving electrodes", H. Schenk et al., MEMS 2000, 13 <sup>th</sup> Int. Micro Electro Mechanical Systems Conf, Miyazaki, Japan, p. 473-478 (2000).
18	<del>but</del>	AF	"Damping of Micro Electrostatic Torsion Mirror Caused by Air-Film Viscosity", N. Uchida et al.
19	<del>but</del>	AG	"Single Crystal Silicon (SCS) MicroMirror Arrays using Deep Silicon Etching and IR Alignment", C.S.B. Lee et al.

**EXAMINER****DATE CONSIDERED**

9/19/02

\* **EXAMINER:** Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

RECEIVED  
FEB 20 2003  
TECHNOLOGY CENTER 2003